



## VaPore® Vacuum Tight Aluminum Castings Historical Summary (through February 2008)

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| <b>Etching Equipment</b><br>Four casting assembly (vacuum chamber, cover, base, vacuum manifold) used as a process chamber in a wafer etching product; two assemblies per system | 1980-present |
| <b>Ion Implanter (high current)</b><br>More than 25 different castings used in wafer handling, beam line, and implant chamber  | 1989-present |
| <b>Flat Panel</b><br>Panel handling and process chamber  | 1996-present |
| <b>Ion Implanter (medium &amp; high current)</b><br>More than 60 different castings used in wafer handling, beam line, and implant chamber                                       | 1987-present |
| <b>Cluster Tool</b><br>Loadlocks and wafer handling chamber  | 1992-present |
| <b>Mass Spectrometry</b><br>Housings, Analyzer Tubes, Loadlocks  | 1998-present |
| <b>Etching Equipment</b><br>Loadlocks, Transfer Chamber  | 1991-present |
| <b>Diffusion Furnace</b><br>Wafer handling chamber   | 1995-present |
| <b>Etching Equipment</b><br>Loadlocks, process chambers, and wafer handling chamber  | 1995-present |
| <b>300mm Equipment</b><br>Loadlocks and wafer handling chambers, Combination Loadlock and Transfer Chamber   | 1998-present |

**Over 4,164 systems utilizing close to 8,328 loadlocks from 1980 to the present, with no field failure reported to us due to casting defects or vacuum leaks.**

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Quality Aluminum Castings Since 1951

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